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**FOR IMMEDIATE RELEASE**

ISSYS, Inc., Awarded Patent for Microneedle Technology

YPSILANTI, MICH., February 2, 2005 - Integrated Sensing Systems, Inc. (ISSYS) announced today that the US Patent Office has granted it a device and method patents (US 6,844,213) entitled "Process of forming a microneedle and microneedle formed thereby."

This patent represents a new method of making robust silicon microneedles and microneedle arrays. The extremely small needles formed with this technique can be employed in painless drug and insulin delivery. Fracture of silicon microneedles fabricated by other institutions has been a problem preventing the wide-spread use of micromachined needles. ISSYS approach greatly reduces this and other barriers to implementing micromachined needles and needle arrays in real medical applications.

According to Dr. Douglas Sparks, ISSYS' executive vice president, "This new microneedle patent compliments ISSYS' other drug infusion technology and products. ISSYS has pioneered new methods of preventing drug infusion errors and delivering lower drug doses using microfluidic technology."

**About ISSYS:** ISSYS is a leader in advanced micromachining technologies for medical devices, microfluidic and scientific analytical sensing applications. Founded in 1995 by world-renowned leaders in MEMS technology, ISSYS is one of the oldest independent MEMS companies in the United States. ISSYS operates a multi-million-dollar, state-of-the-art MEMS fabrication facility near Ann Arbor, Michigan. An ISO 9000:2001 certified organization, ISSYS is a vertically integrated company dedicated to developing and manufacturing system-level products based on MEMS technology (MEMS Inside). For more information, visit:

<http://www.mems-issys.com/>.

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